IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

re patent application of

byuki Kunishima, et al.

Serial No.:

10/613,069

Group Art Unit:

Not Yet Assigned

Filing Date:

July 7, 2003

Examiner:

Unknown

For:

SEMICONDUCTOR DEVICE AND MANUFACTURING METHOD

THEREOF

Honorable Commissioner of Patent Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

Under the provisions of 37 CFR §1.97 through §1.99 and pursuant to applicant's duty of disclosure under 37 CFR §1.56, applicant respectfully brings the following document listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application. Copy of the listed document is provided herewith for the convenience of the Examiner.

This citation does not constitute an admission that the references are relevant or material to the claims. They are only cited as constituting related art of which the applicant is aware.

It is respectfully requested that the listed references be considered by the Examiner and formally made of record in this application.

Please charge any deficiencies in fees and credit any overpayment of fees to Attorney's Deposit Account No. 50-0481.

Date:

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•	INFOR	RMATION DISCLOSURE	CITATION	NE-70085U Applicant(s)		Application Number 10/613,069	
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			TRADEN	ATENT DOCUMENTS			
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	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation YES NO
L			TO	THER DOCUMENTS (Including	Author, Title, Da	ite, Pertinent Pa	ges, Etc.)
T. Takewaki, et al., "Formation of gian-grain copper interconnects by a low-energy ion bombardment process for high-spee ULSIs", Materials Chemistry and Physics 41 (1995) pp. 182-191.							
EXAMINER	<u> </u>			DATE CONSIDERED			
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Form PTO-A820 (also form PTO-1449)

P09A/REV04

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